

PATENT ASSIGNMENT COVER SHEET

Electronic Version v1.1
 Stylesheet Version v1.2

EPAS ID: PAT2938785

SUBMISSION TYPE:	NEW ASSIGNMENT	
NATURE OF CONVEYANCE:	ASSIGNMENT OF JOINT OWNERSHIP	
CONVEYING PARTY DATA		
Name		Execution Date
MOLECULAR IMPRINTS, INC.		07/10/2014
RECEIVING PARTY DATA		
Name:	MII NEWCO, INC.	
Street Address:	1807-C WEST BRAKER LN	
City:	AUSTIN	
State/Country:	TEXAS	
Postal Code:	78708	
PROPERTY NUMBERS Total: 204		
Property Type	Number	
Application Number:	11560266	
Application Number:	11694612	
Application Number:	12047572	
Application Number:	12275998	
Application Number:	12327618	
Application Number:	12364979	
Application Number:	12603819	
Application Number:	12604517	
Application Number:	12604866	
Application Number:	12607564	
Application Number:	12817787	
Application Number:	12828498	
Application Number:	12835009	
Application Number:	12954376	
Application Number:	13017259	
Application Number:	12987196	
Application Number:	13014508	
Application Number:	13015379	
Application Number:	13106407	
Application Number:	13095514	
Application Number:	11143092	

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Property Type	Number
Application Number:	13105695
Application Number:	13172350
Application Number:	13178268
Application Number:	13227205
Application Number:	13228298
Application Number:	13226635
Application Number:	13245288
Application Number:	14216017
Application Number:	13455966
Application Number:	13446364
Application Number:	13546622
Application Number:	13720315
Application Number:	13743772
Application Number:	13773217
Application Number:	13754015
Application Number:	13910547
Application Number:	14150261
Patent Number:	8545709
Patent Number:	8309008
Patent Number:	8231821
Patent Number:	8432548
Patent Number:	8387482
Patent Number:	8512585
Patent Number:	8361546
Patent Number:	8237133
Patent Number:	8361371
Patent Number:	8415010
Patent Number:	8142702
Patent Number:	8470188
Patent Number:	8541053
Patent Number:	8616873
Patent Number:	8628712
Patent Number:	8556616
Patent Number:	7985530
Patent Number:	8119052
Patent Number:	8512797
Patent Number:	8589126
Patent Number:	8345242
Patent Number:	8021594

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REEL: 033329 FRAME: 0281

Property Type	Number
Patent Number:	8012394
Patent Number:	7935292
Patent Number:	8123514
Patent Number:	8142850
Patent Number:	8066930
Patent Number:	8349241
Patent Number:	8480933
Patent Number:	8142704
Patent Number:	7981481
Patent Number:	8152511
Patent Number:	8075299
Patent Number:	7798801
Patent Number:	8033815
Patent Number:	7635263
Patent Number:	8033813
Patent Number:	7170589
Patent Number:	7420654
Patent Number:	7298456
Patent Number:	7462028
Patent Number:	7768624
Patent Number:	7261830
Patent Number:	7636999
Patent Number:	7635445
Patent Number:	7641840
Patent Number:	6932934
Patent Number:	7708926
Patent Number:	7910042
Patent Number:	8057725
Patent Number:	7387508
Patent Number:	8109753
Patent Number:	7670529
Patent Number:	8109754
Patent Number:	6871558
Patent Number:	7670530
Patent Number:	6990870
Patent Number:	7036389
Patent Number:	7691313
Patent Number:	8282383
Patent Number:	7150622

PATENT

REEL: 033329 FRAME: 0282

Property Type	Number
Patent Number:	7338275
Patent Number:	7442336
Patent Number:	6982783
Patent Number:	7019819
Patent Number:	7224443
Patent Number:	6980282
Patent Number:	7157036
Patent Number:	7670534
Patent Number:	7931846
Patent Number:	7316554
Patent Number:	8215946
Patent Number:	7803308
Patent Number:	7906058
Patent Number:	7256131
Patent Number:	7309225
Patent Number:	7473090
Patent Number:	7811505
Patent Number:	7019835
Patent Number:	7270533
Patent Number:	7090716
Patent Number:	6805054
Patent Number:	7041604
Patent Number:	7837907
Patent Number:	8147731
Patent Number:	7785096
Patent Number:	7292326
Patent Number:	7630067
Patent Number:	7880872
Patent Number:	7323130
Patent Number:	7874831
Patent Number:	6929762
Patent Number:	7906274
Patent Number:	7547398
Patent Number:	7854867
Patent Number:	7665981
Patent Number:	8012395
Patent Number:	7281919
Patent Number:	7357876
Patent Number:	7927541

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Property Type	Number
Patent Number:	7186656
Patent Number:	7323417
Patent Number:	7396475
Patent Number:	7105452
Patent Number:	7547504
Patent Number:	7179396
Patent Number:	7261831
Patent Number:	7670953
Patent Number:	7858528
Patent Number:	7947608
Patent Number:	7802978
Patent Number:	7077992
Patent Number:	8318066
Patent Number:	7727453
Patent Number:	7943081
Patent Number:	7179079
Patent Number:	7699598
Patent Number:	7491637
Patent Number:	7780893
Patent Number:	7795132
Patent Number:	7136150
Patent Number:	7815824
Patent Number:	7241395
Patent Number:	6900881
Patent Number:	6916584
Patent Number:	7070405
Patent Number:	7244386
Patent Number:	7205244
Patent Number:	7452574
Patent Number:	7252777
Patent Number:	7785526
Patent Number:	8366434
Patent Number:	7132225
Patent Number:	7037639
Patent Number:	7259102
Patent Number:	7252715
Patent Number:	7027156
Patent Number:	7281921
Patent Number:	7071088

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REEL: 033329 FRAME: 0284

Property Type	Number
Patent Number:	7279113
Patent Number:	7140861
Patent Number:	7759407
Patent Number:	8557351
Patent Number:	7845931
Patent Number:	8211214
Patent Number:	8268220
Patent Number:	7837921
Patent Number:	7939131
Patent Number:	8142703
Patent Number:	7307118
Patent Number:	7122079
Patent Number:	7906180
Patent Number:	7282550
Patent Number:	7122482
Application Number:	11734542
Application Number:	12326709
Application Number:	13098959
Patent Number:	8187515
Patent Number:	8529778
Patent Number:	8076386
Application Number:	12854359
Application Number:	13105422
Application Number:	13289601
Application Number:	13290770
Application Number:	13398442
Application Number:	14021463

CORRESPONDENCE DATA

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NAME OF SUBMITTER:	CAMERON A. KING
SIGNATURE:	/Cameron A. King/
DATE SIGNED:	07/15/2014

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REEL: 033329 FRAME: 0285

Total Attachments: 18

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CONFIRMATORY ASSIGNMENT OF JOINT PATENT OWNERSHIP

This Confirmatory Assignment of Joint Patent Ownership (this "Confirmatory Assignment"), effective April 17, 2014 (the "Effective Date"), is by and between MOLECULAR IMPRINTS, INC., a Delaware corporation having a principal place of business at 1807-C West Braker Lane, Austin, Texas 78758-3650 (hereinafter "Assignor"), and MII NEWCO, INC., a Delaware corporation having a principal place of business at 1807-C West Braker Lane, Austin, Texas 78758-3650 (hereinafter "Assignee").

WHEREAS, pursuant to that certain Technology and Intellectual Property Transfer Agreement between Assignor and Assignee dated April 17, 2014 (the "Agreement"), Assignor assigned to Assignee an undivided, one-half interest in and to Assignor's Intellectual Property Rights, including but not limited to Assignor's rights in the patents and patent applications listed in Exhibit A hereto, and to any foreign counterparts, any divisional, continuation, continuations-in-part, renewals, all patents issuing from any of the foregoing patent applications, all patents that claim priority to or have common priority with any such patents, all reissues, reexaminations and extensions, and all patents on inventions claimed in any of the foregoing and patents thereon, in each case regardless of whether in existence prior to, as of or after the Effective Date, and in each case to the extent that the same claim subject matter that was disclosed in an application described in the applicable patent (collectively the "Patents").

NOW, THEREFORE, in consideration of good and valuable consideration as is further detailed in the Agreement, the receipt and sufficiency of which is hereby acknowledged, Assignor hereby confirms having assigned to Assignee an undivided, one-half interest in and to the Patents.

IN WITNESS WHEREOF, the parties have caused this Confirmatory Assignment to be executed by their duly authorized representatives.

MOLECULAR IMPRINTS, INC.

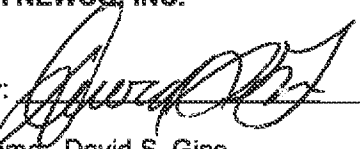
By: 

Name: C.M. Melliar-Smith

Title: President & CEO

Date: 7/10/14

MI NEWCO, INC.

By: 

Name: David S. Gino

Title: CEO

Date: 7/10/14

Exhibit A

App. No.	Pat No.	Filing Date	Issue Date	Title	Inventors
11/560,266		15-Nov-2006		Methods and Compositions for Providing Preferential Adhesion and Release of Adjacent Surfaces	Xu, Frank Y.
11/694,612		30-Mar-2007		Tessellated Patterns in Imprint Lithography	Sreenivasan, Sidigata V.; Schumaker, Philip D.; McMackin, Ian Matthew
12/047,572		13-Mar-2008		Methods of Exposure for the Purpose of Thermal Management for Imprint Lithography Processes	Sreenivasan, Sidigata V.; Choi, Byung-Jin
12/275,998		21-Nov-2008		POROUS TEMPLATE AND IMPRINTING STACK FOR NANO-IMPRINT LITHOGRAPHY	Xu, Frank Y.; Liu, Weijun; Fletcher, Edward B.; Sreenivasan, Sidigata V.; Choi Byung-Jin; Khusnatdinov, Niyaz; Cherala, Anshuman; Selinidis, Kosta S.
12/327,618		3-Dec-2008		High Throughput Imprint Based on Contact Line Motion Tracking Control	Lu, Xiaoming; Schumaker, Philip D.
12/364,979		3-Feb-2009		Controlling Template Surface Composition in Nano-Imprint Lithography	Xu, Frank Y.; Liu, Weijun
12/603,819		22-Oct-2009		FLUID TRANSPORT AND DISPENSING	Truskett, Van Nguyen; Shackleton, Steven C. Khusnatdinov, Niyaz; Xu, Frank Y.; Meisl, Mario Johannes; Miller, Michael N.; Thompson, Ecron D.; Schmid, Gerard M.; Nimmakayala, Pawan Kumar; Lu, Xiaoming; Choi, Byung-Jin
12/604,517		23-Oct-2009		Strain and Kinetics Control During Separation Phase of Imprint Process	Schmid, Gerard M.; Resnick, Douglas J.; Sreenivasan, Sidigata V.; Xu, Frank Y.
12/604,866		23-Oct-2009		Imprint Lithography Template	Miller, Michael N.; Brooks, Cynthia B.; Brown, Laura Anne; Schmid, Gerard M.
12/607,564		28-Oct-2009		Master Template Replication	GanapathiSubramanian, Mahadevan; Choi, Byung-Jin
12/817,787		17-Jun-2010		Dual Zone Template Chuck	

App. No.	Pat No.	Filing Date	Issue Date	Title	Inventors
12/828,498		1-Jul-2010		Chucking System with Recessed Support Feature	GanapathiSubramanian, Mahadevan, Meissl, Mario Johannes, Parga, Avnash, Choi, Byung-jin
12/835,009		13-Jul-2010		Residual Layer Thickness Measurement and Correction	Jones, Christopher Ellis; Khusnatdinov, Niyaz; Johnson, Stephen C.; Schumaker, Philip D.; Lad, Pankaj B.
12/954,376		24-Nov-2010		Adhesion Layers in Nanoimprint Lithography	Ye, Zhengmao; Xu, Frank Y.; LaBrake, Dwayne L.; Selindis, Kosta S.
13/017,259		31-Jan-2011		Nanoimprint Lithography Processes	Xu, Frank Y.; Sreenivasan, Sidigata V.
61/889,241		10-Oct-2013		Aluminum Dry Etch Process for Making Wire Grid Polarizers	Yang, Shuqiang
12/987,196		10-Jan-2011		Systems and Methods for Substrate Formation	Choi, Byung-jin
13/014,508		26-Jan-2011		Methods and Systems of Material Removal and Pattern Transfer	Schmid, Gerard M.; Miller, Michael N.; Choi, Byung-jin; Resnick, Douglas J.; Sreenivasan, Sidigata V.; Xu, Frank Y.; Donaldson, Darren D.
13/015,379		27-Jan-2011		Roll-to-Roll Imprint Lithography and Purging System	Choi, Byung-jin
13/106,407		12-May-2011		Reducing Adhesion between a Conformable Region and a Mold	Xu, Frank Y.; Miller, Michael N.
13/095,514		27-Apr-2011		Safe separation for nano imprinting	jin, Se-Hyuk; GanapathiSubramanian, Mahadevan; Fletcher, Edward B.; Khusnatdinov, Niyaz; Schmid, Gerard M.; Meissl, Mario Johannes; Cherala, Anshuman; Xu, Frank Y.; Choi, Byung-jin; Sreenivasan, Sidigata V.
11/143,092		2-Jun-2005		Fluid Dispensing and Drop-On-Demand Dispensing for Nano-Scale Manufacturing	Lad, Pankaj B.; McMackin, Ian Matthew; Truskett, Van Nguyen; Sreenivasan, Truskett, Van Nguyen; Sreenivasan, Duane; Schumaker, Philip D.; Fletcher, Edward B.
13/105,695		11-May-2011		Backside Contact Solar Cell	Miller, Michael N.; Sreenivasan, Sidigata V.; Xu, Frank Y.; Schmid, Gerard M.

App. No.	Pat No.	Filing Date	Issue Date	Title	Inventors
13/172,350		29-Jun-2011		Low-K Dielectric Functional Imprinting Materials	Xu, Frank Y.; Chun, Jun Sung; Watts, Michael P.C.
13/178,268		7-Jul-2011		Contaminate Detection and Substrate Cleaning Methods of Cleaning Hard Disk Drive Substrates for Nanoimprint Lithography	Khushnatinov, Miyaz, LaBrake, Dwayne L.
13/227,205		7-Sep-2011			Ye, Zhengmao; Ramos, Rick
13/228,298		8-Sep-2011		Vapor Delivery System For Use in Imprint Lithography	Ye, Zhengmao; Ramos, Rick; Fletcher, Edward B.; Jones, Christopher Ellis; LaBrake, Dwayne L.
13/226,635		7-Sep-2011		Release Agent Partition Control in Imprint Lithography	Xu, Frank Y.; Liu, Weijun
13/245,288		26-Sep-2011		High Contrast Alignment Marks Through Multiple Stage Imprinting	Imhof, Joseph Michael; Selimidis, Kosta S.; LaBrake, Dwayne L.
14/216,017		17-Mar-2014		Nano Imprinting with Reusable Polymer Template with Metallic or Oxide Coating	Ahn, Se Hyun; Choi, Byung-Jin; Xu, Frank Y.
13/455,966		25-Apr-2012		Optically Absorptive Material for Alignment Marks	Khushnatinov, Miyaz, Selimidis, Kosta S.; Imhof, Joseph Michael; LaBrake, Dwayne L.
13/446,364		13-Apr-2012		Photocatalytic Reactions in Nano-Imprint Lithography Processes	Fletcher, Edward B.; Xu, Frank Y.
13/546,622		11-Jul-2012		Reduced Residual Formation in Etched Multi-Layer Stacks	Xu, Frank Y.; Liu, Weijun; Brooks, Cynthia B.; LaBrake, Dwayne L.; Lentz, David James
61/921,647		30-Dec-2013		Methods for Uniform Imprint Pattern Transfer of Sub-20 nm Features	Ye, Zhengmao; LaBrake, Dwayne L.
13/720,315		19-Dec-2012		FABRICATION OF SEAMLESS LARGE AREA MASTER TEMPLATES FOR IMPRINT LITHOGRAPHY USING STEP AND REPEAT TOOLS	Resnick, Douglas J.; Miller, Michael N.; Xu, Frank Y.
13/743,772		17-Jan-2013		Extrusion Reduction in Imprint Lithography	Khushnatinov, Miyaz, Jones, Christopher Ellis; Perez, Joseph G.; LaBrake, Dwayne L.; McMackin, Ian Matthew

App. No.	Pat No.	Filing Date	Issue Date	Title	Inventors
13/773,217		21-Feb-2013		Large Area Imprint Lithography	Choi, Byung-Jin; Ahn, Se Hyun; GanapathiSubramanian, Mahadevan; Miller, Michael N.; Sreenivasan, Sidigata V.
13/754,015		30-Jan-2013		Fabrication of High-Throughput Nano-Imprint Lithography Templates	Fletcher, Edward B.; Xu, Frank Y.; Liu, Weijun; Wan, Fen; Menezes, Marlon; Selinidis, Kosta
13/910,547		5-Jun-2013		Nano-Imprint Lithography Templates	Khushnatinov, Niyaz; Liu, Weijun; Xu, Frank Y.; Fletcher, Edward B.; Wan, Fen
14/150,261		8-Jan-2014		Strain and Kinetics Control During Separation Phase of Imprint Process	Khushnatinov, Niyaz; Xu, Frank Y.; Meissl, Mario Johannes; Miller, Michael N.; Thompson, Ecron D.; Schmid, Gerard M.; Nimmakayala, Pawan Kumar; Lu, Xiaoming; Choi, Byung-Jin
8,545,709		1-Oct-2013		Critical Dimension Control During Template Formation	Brooks, Cynthia B.; LaBrake, Dwayne L.; Khushnatinov, Niyaz; Miller, Michael N.; Sreenivasan, Sidigata V.; Lentz, David James; Xu, Frank Y.
8,309,008		13-Nov-2012		Separation in an Imprint Lithography Process	Choi, Byung-Jin; GanapathiSubramanian, Mahadevan
8,231,821		31-Jul-2012		Substrate Alignment	Choi, Byung-Jin; Nimmakayala, Pawan Kumar; GanapathiSubramanian, Mahadevan
8,432,548		30-Apr-2013		Alignment for Edge Field Nano-Imprinting	Choi, Byung-Jin; Nimmakayala, Pawan Kumar; Schumaker, Philip D.
8,387,482		5-Mar-2013		Method and System to Control Movement of a Body for Nano-Scale Manufacturing	Choi, Byung-Jin; Sreenivasan, Sidigata V.
8,512,585		20-Aug-2013		Template Pillar Formation	Doyle, Gary F.; Schmid, Gerard M.; Miller, Michael N.; Resnick, Douglas J.; LaBrake, Dwayne L.
8,361,546		29-Jan-2013		Facilitating Adhesion Between Substrate and Patterned Layer	Fletcher, Edward B.; Ye, Zhengmao; LaBrake, Dwayne L.; Xu, Frank Y.
8,237,133		7-Aug-2012		Energy Sources for Curing in an Imprint Lithography System	GanapathiSubramanian, Mahadevan; Choi, Byung-Jin; Wang, Liang; Ruiz, Alex

App. No.	Pat No.	Filing Date	Issue Date	Title	Inventors
	8,361,371		29-Jan-2013	Extrusion Reduction in Imprint Lithography	Khushnadinov, Niyaz; Jones, Christopher Ellis; Perez, Joseph G.; Labrake, Dwayne L.; McMackin, Ian Matthew
	8,445,010		9-Apr-2013	Nano-Imprint Lithography Stack with Enhanced Adhesion Between Silicon-Containing and Non-Silicon Containing Layers	Liu, Weijun; Xu, Frank Y.
	8,142,702		27-Mar-2012	Solvent-Assisted Layer Formation for Imprint Lithography	Liu, Weijun; Xu, Frank Y.; Fletcher, Edward B.
	8,470,188		25-Jun-2013	Nano-Imprint Lithography Templates	Menezes, Marlon
	8,541,053		24-Sep-2013	Enhanced Densification of Silicon Oxide Layers	Menezes, Marlon; Xu, Frank Y.; Wan, Fen
	8,616,873		31-Dec-2013	Micro-Conformal Templates for Nanoimprint Lithography	Miller, Michael N.; Xu, Frank Y.; Stacey, Nicholas
	8,628,712		14-Jan-2014	Misalignment Management	Mokaberl, Babak
				Template Having a Varying Thickness to Facilitate Expelling a Gas Positioned Between a Substrate and the Template	Resnick, Douglas J.; Meisl, Mario Johannes; Choi, Byung-Jin; Sreenivasan, Sidigata V.
	8,556,616		15-Oct-2013		
	7,985,530		26-Jul-2011	Etch-enhanced technique for lift-off patterning	Schmid, Gerard M.; Resnick, Douglas J.
	8,119,052		21-Feb-2012	Drop Pattern Generation for Imprint Lithography	Schumaker, Philip D.
	8,512,797		20-Aug-2013	Drop Pattern Generation with Edge Weighting	Schumaker, Philip D.
				Robust Optimization to Generate Drop Patterns in Imprint Lithography Which Are Tolerant of Variations in Drop Volume and Drop Placement	Schumaker, Philip D.
	8,589,126		19-Nov-2013	Optical System for Use in Stage Control	Schumaker, Philip D.; Mokaberl, Babak
	8,345,242		1-Jan-2013		
	8,021,594		20-Sep-2011	Preserving Filled Features When Vacuum Wiping	Shackleton, Steven G.; Lad, Pankaj B.; McMackin, Ian Matthew; Xu, Frank Y.; Sreenivasan, Sidigata V.
	8,012,394		6-Sep-2011	Template Pattern Density Doubling	Sreenivasan, Sidigata V.
	7,935,292		3-May-2011	Imprinting of Partial Fields at the Edge of the Wafer	Sreenivasan, Sidigata V.; Choi, Byung-Jin

App. No.	Pat. No.	Filing Date	Issue Date	Title	Inventors
	8,123,514		28-Feb-2012	Conforming Template for Patterning Liquids Disposed on Substrates	Sreenivasan, Sidigata V.; Choi, Byung-Jin; Voisin, Ronald D.
	8,142,850		27-Mar-2012	Patterning a Plurality of Fields on a Substrate to Compensate for Differing Evaporation Times	Sreenivasan, Sidigata V.; Schumaker, Philip D.
	8,066,930		29-Nov-2011	Forming a Layer on a Substrate	Sreenivasan, Sidigata V.; Watts, Michael P.C.
	8,349,241		8-Jan-2013	Method to Arrange Features on a Substrate to Replicate Features Having Minimal Dimensional Variability	Sreenivasan, Sidigata V.; Watts, Michael P.C.; Truskett, Van Nguyen; Johnson, Stephen C.; Khushnatinov, Miyaz; Simpson, Logan
	8,480,933		9-Jul-2013	Fluid Dispense Device Calibration	Wang, Liang; Choi, Yeong-jun; Choi, Byung-jin
	8,142,704		27-Mar-2012	Imprint Lithography System and Method	Xu, Frank Y.; McMackin, Ian Matthew; Lad, Pankaj B.; Watts, Michael P.C.
	7,981,481		19-Jul-2011	Method for Controlling Distribution of Fluid Components on a Body	Xu, Frank Y.; McMackin, Ian Matthew; Lad, Pankaj B.; Watts, Michael P.C.
	8,152,511		10-Apr-2012	Composition to Reduce Adhesion Between a Conformable Region and a Mold	Xu, Frank Y.; Miller, Michael N.
	8,075,299		13-Dec-2011	Reduction of Stress During Template Separation	Xu, Frank Y.; Sreenivasan, Sidigata V.
	7,798,801		21-Sep-2010	Chucking System for Nano-Manufacturing	Babbs, Daniel A.; Choi, Byung-jin; Cherala, Anshuman
	8,033,815		11-Oct-2011	Chucking System for Nano-Manufacturing	Babbs, Daniel A.; Choi, Byung-jin; Cherala, Anshuman
	7,635,263		22-Dec-2009	Chucking System Comprising an Array of Fluid Chambers	Cherala, Anshuman; Choi, Byung-jin; Lad, Pankaj B.; Shackleton, Steven C
	8,033,813		11-Oct-2011	Chucking System Comprising an Array of Fluid Chambers	Cherala, Anshuman; Choi, Byung-jin; Lad, Pankaj B.; Shackleton, Steven C
	7,170,589		30-Jan-2007	Apparatus to Vary Dimensions of a Substrate During Nano-Scale Manufacturing	Cherala, Anshuman; Choi, Byung-jin; Nimmakayala, Pawan Kumar; Meisli, Mario Johannes; Sreenivasan, Sidigata V.

App. No.	Pat No.	Filing Date	Issue Date	Title	Inventors
	7,420,654		2-Sep-2008	Method of Varying Dimensions of a Substrate During Nano-Scale Manufacturing	Cherala, Anshuman; Choi, Byung-Jin; Nimmakayala, Pawan Kumar; Meissl, Mario Johannes; Sreenivasan, Sidigata V.
	7,298,456		20-Nov-2007	System for Varying Dimensions of a Substrate During Nano-Scale Manufacturing	Cherala, Anshuman; Choi, Byung-Jin; Nimmakayala, Pawan Kumar; Meissl, Mario Johannes; Sreenivasan, Sidigata V.
	7,462,028		9-Dec-2008	Partial Vacuum Environment Imprinting	Cherala, Anshuman; Lad, Pankaj B.; McMackin, Ian M.; Choi, Byung-Jin
				METHOD FOR OBTAINING FORCE COMBINATIONS FOR TEMPLATE DEFORMATION USING NULLSPACE AND METHODS OPTIMIZATION TECHNIQUES	Cherala, Anshuman; Sreenivasan, Sidigata V.; Choi, Byung-Jin; Thompson, Ecron D.
	7,768,624		3-Aug-2010	Applying Imprinting Material to Substrates Employing Electromagnetic Fields	Cherala, Anshuman; Sreenivasan, Sidigata V.; Schumaker, Norman E.
	7,261,830		28-Aug-2007	Method of Retaining a Substrate to a Wafer	Choi, Byung-Jin; Cherala, Anshuman; Babbs, Daniel A.
	7,636,999		29-Dec-2009	Chuck	Choi, Byung-Jin; Cherala, Anshuman; Choi, Yeong-jun; Meissl, Mario Johannes; Sreenivasan, Sidigata V.; Schumaker, Norman E.; Lu, Xiaoming; McMackin, Ian Matthew; Babbs, Daniel A.
	7,635,445		22-Dec-2009	Methods of Separating a Mold from a Solidified Layer Disposed on a Substrate	Choi, Byung-Jin; GanapathiSubramanian, Mahadevan; Choi, Yeong-jun; Meissl, Mario J.
	7,641,840		5-Jan-2010	METHOD FOR EXPELLING GAS POSITIONED BETWEEN A SUBSTRATE AND A MOLD	
				Formation of Discontinuous Films During an Imprint Lithography Process	Choi, Byung-Jin; Meissl, Mario Johannes; Sreenivasan, Sidigata V.; Watts, Michael P.C.
	6,932,934		23-Aug-2005		
	7,708,926		4-May-2010	Capillary Imprinting Technique	Choi, Byung-Jin; Sreenivasan, Sidigata V.
	7,910,042		22-Mar-2011	Capillary Imprinting Technique	Choi, Byung-Jin; Sreenivasan, Sidigata V.
	8,057,725		15-Nov-2011	Capillary Imprinting Technique	Choi, Byung-Jin; Sreenivasan, Sidigata V.
	7,387,508		17-Jun-2008	Compliant Device for Nano-Scale Manufacturing	Choi, Byung-Jin; Sreenivasan, Sidigata V.

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	8,109,753		7-Feb-2012	Double-Sided Nano-Imprint Lithography System	Choi, Byung-Jin; Sreenivasan, Sidigata V.
	7,670,529		2-Mar-2010	Method and System for Double-Sided Patterning of Substrates	Choi, Byung-Jin; Sreenivasan, Sidigata V.
	8,109,754		7-Feb-2012	Method and System for Double-Sided Patterning of Substrates	Choi, Byung-Jin; Sreenivasan, Sidigata V.
				Method for Determining Characteristics of Substrates	
	6,871,558		29-Mar-2005	Employing Fluid Geometries	Choi, Byung-Jin; Sreenivasan, Sidigata V.
	7,670,530		2-Mar-2010	Patterning Substrates Employing Multiple Chucks	Choi, Byung-Jin; Sreenivasan, Sidigata V.
	6,990,870		31-Jan-2006	System for Determining Characteristics of Substrates Employing Fluid Geometries	Choi, Byung-Jin; Sreenivasan, Sidigata V.
	7,036,389		2-May-2006	System for Determining Characteristics of Substrates Employing Fluid Geometries	Choi, Byung-Jin; Sreenivasan, Sidigata V.
	7,691,313		6-Apr-2010	Method for Expelling Gas Positioned Between a Substrate and a Mold	Choi, Byung-Jin; Sreenivasan, Sidigata V.; McMackin, Ian Matthew; Lad, Pankaj B.
	8,282,383		9-Oct-2012	Method for Expelling Gas Positioned Between a Substrate and a Mold	Choi, Byung-Jin; Sreenivasan, Sidigata V.; McMackin, Ian Matthew; Lad, Pankaj B.
	7,150,622		19-Dec-2006	Systems for Magnification and Distortion Correction for Imprint Lithography Processes	Choi, Byung-Jin; Sreenivasan, Sidigata V.; Meissl, Mario Johannes
				Formation of Discontinuous Films During an Imprint Lithography Process	Choi, Byung-Jin; Sreenivasan, Sidigata V.; Meissl, Mario Johannes; Watts, Michael P.C.
	7,338,275		4-Mar-2008	Capillary Imprinting Technique	Choi, Byung-Jin; Sreenivasan, Sidigata V.; Watts, Michael P.C.
	7,442,336		28-Oct-2008		
	6,982,783		3-Jan-2006	Chucking System for Modulating Shapes of Substrates	Choi, Byung-Jin; Voisin, Ronald D.; Sreenivasan, Sidigata V.; Watts, Michael P.C.; Babb, Daniel A.; Meissl, Mario Johannes; Bailey, Hillman L.; Schumaker, Norman E.

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	7,019,819		28-Mar-2006	Chucking System for Modulating Shapes of Substrates	Choi, Byung-jin; Voisin, Ronald D.; Sreenivasan, Sidigata V.; Watts, Michael P.C.; Babbs, Daniel A.; Meissl, Mario Johannes; Bailey, Hillman L.; Schumaker, Norman E.
	7,224,443		29-May-2007	Imprint Lithography Substrate Processing Tool for Modulating Shapes of Substrates	Choi, Byung-jin; Voisin, Ronald D.; Sreenivasan, Sidigata V.; Watts, Michael P.C.; Babbs, Daniel A.; Meissl, Mario Johannes; Bailey, Hillman L.; Schumaker, Norman E.
	6,980,282		27-Dec-2005	Method for Modulating Shapes of Substrates	Choi, Byung-jin; Xu, Frank Y.; Stacey, Nicholas A.; Truskett, Van Nguyen; Watts, Michael P.C.
	7,157,036		2-Jan-2007	Method to Reduce Adhesion Between a Conformable Region and a Pattern of a Mold	Choi, Yeong-jun; Choi, Byung-jin
	7,670,534		2-Mar-2010	Method to Control an Atmosphere Between a Body and a Substrate	Choi, Yeong-jun; Choi, Byung-jin
	7,931,846		26-Apr-2011	Method to Control an Atmosphere Between a Body and a Substrate	Choi, Yeong-jun; Choi, Byung-jin
	7,316,554		8-Jan-2008	System to Control an Atmosphere Between a Body and a Substrate	Choi, Yeong-jun; Choi, Byung-jin
	8,215,946		10-Jul-2012	Imprint Lithography System and Method	GanapathSubramanian, Mahadevan; Choi, Byung-jin; Meissl, Mario J.
	7,803,308		28-Sep-2010	Technique for Separating a Mold from Solidified Imprinting Material	GanapathSubramanian, Mahadevan; Choi, Byung-jin; Miller, Michael N.; Stacey, Nicholas A.
	7,906,058		15-Mar-2011	Bifurcated Contact Printing Technique	GanapathSubramanian, Mahadevan; Choi, Byung-jin; Miller, Michael N.; Stacey, Nicholas A.; Watts, Michael P.C.
	7,256,131		14-Aug-2007	Method of Controlling the Critical Dimension of Structures Formed on a Substrate	LaBrake, Dwayne L.

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	7,309,225		18-Dec-2007	Moat system for an imprint lithography template	McMackin, Ian Matthew; Lad, Pankaj B.
	7,473,090		6-Jan-2009	Imprint Lithography Template to Facilitate Control of Liquid Movement	McMackin, Ian Matthew; Lad, Pankaj B.; Truskett, Van Nguyen
	7,811,505		12-Oct-2010	Method For Fast Filling Of Templates For Imprint Lithography Using On Template Dispense	McMackin, Ian Matthew; Lad, Pankaj B.; Truskett, Van Nguyen
	7,019,835		28-Mar-2006	Method and System to Measure Characteristics of a Film Disposed on a Substrate	McMackin, Ian Matthew; Stacey, Nicholas A.; Babb, Daniel A.; Voth, Duane; Watts, Michael P.C.; Truskett, Van Nguyen; Xu, Frank Y.; Voisin, Ronald D.; Lad, Pankaj B.
	7,270,533		18-Sep-2007	System for Creating a Turbulent Flow of Fluid Between a Mold and a Substrate	McMackin, Ian Matthew; Stacey, Nicholas A.; Babb, Daniel A.; Voth, Duane; Watts, Michael P.C.; Truskett, Van Nguyen; Xu, Frank Y.; Voisin, Ronald D.; Lad, Pankaj B.; Ezekoye, Ofofike A.
	7,090,716		15-Aug-2006	Single Phase Fluid Imprint Lithography Method	Meissl, Mario Johannes; Choi, Byung-Jin; Babb, Daniel A.; Bailey, Hillman
	6,805,054		19-Oct-2004	Method, System and Holder for Transferring Templates During Imprint Lithography Processes	Meissl, Mario Johannes; Choi, Byung-Jin; Babb, Daniel A.; Bailey, Hillman
	7,041,604		9-May-2006	Method of Patterning Surfaces While Providing Greater Control of Recess Anisotropy	Miller, Michael N.; Stacey, Nicholas A.
	7,837,907		23-Nov-2010	Alignment System and Method for a Substrate in a Nano-Imprint Process	Nimmakayala, Pawan Kumar; Choi, Byung-Jin
	8,147,731		3-Apr-2012	Alignment System and Method for a Substrate in a Nano-Imprint Process	Nimmakayala, Pawan Kumar; Choi, Byung-Jin; Nimmakayala, Pawan Kumar; Choi, Byung-Jin; Raftery, Tom H.; Schumaker, Philip D.
	7,785,096		31-Aug-2010	Enhanced Multi Channel Alignment	

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	7,292,326		6-Nov-2007	Interferometric Analysis for the Manufacture of Nano-Scale Devices	Nimmakayala, Pawan Kumar; Raftery, Tom H.; Aghili, Alireza; Choi, Byung-Jin; Schumaker, Philip; Babbs, Daniel A.
	7,630,067		8-Dec-2009	Interferometric Analysis for the Manufacture of Nano-Scale Devices	Nimmakayala, Pawan Kumar; Raftery, Tom H.; Aghili, Alireza; Choi, Byung-Jin; Schumaker, Philip; Babbs, Daniel A.; Truskett, Van N.
	7,880,872		1-Feb-2011	Interferometric Analysis for the Manufacture of Nano-Scale Devices	Nimmakayala, Pawan Kumar; Raftery, Tom H.; Aghili, Alireza; Choi, Byung-Jin; Schumaker, Philip; Babbs, Daniel A.; Truskett, Van N.
	7,323,130		29-Jan-2008	Magnification Correction Employing Out-Of-Plane Distortion of a Substrate	Nimmakayala, Pawan Kumar; Sreenivasan, Sidigata V.; Choi, Byung-Jin; Cherala, Anshuman
	7,874,831		25-Jan-2011	Template Having a Silicon Nitride, Silicon Carbide or Silicon Oxynitride Film	Resnick, Douglas J.; Meissl, Mario Johannes; Sellinidis, Kosta S.; Xu, Frank Y.
	6,929,762		16-Aug-2005	Method of Reducing Pattern Distortions During Imprint Lithography Processes	Rubin, Daniel I.
	7,906,274		15-Mar-2011	Method of Creating a Template Employing a Lift-Off Process	Schmid, Gerard M.; Resnick, Douglas J.; Miller, Michael N.
	7,547,398		16-Jun-2009	Self-Aligned Process for Fabricating Imprint Templates Containing Various Etched Features	Schmid, Gerard M.; Stacey, Nicholas A.; Resnick, Douglas J.; Voisin, Ronald D.; Myron, Lawrence J.
	7,854,867		21-Dec-2010	Method for Detecting a Particle in a Nanoimprint Lithography System	Schumaker, Philip D.
	7,665,981		23-Feb-2010	System to Transfer a Template Transfer Body between a Motion Stage and a Docking Plate	Schumaker, Philip D.; Fancello, Angelo; Kim, Jae H.; Choi, Byung-Jin; Babbs, Daniel A.
	8,012,395		6-Sep-2011	Template Having Alignment Marks Formed of Contrast Material	Sellinidis, Kosta S.; Choi, Byung-Jin; Schmid, Gerard M.; Thompson, Eeron D.; McMackin, Ian Matthew

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	7,281,919		16-Oct-2007	System for Controlling a Volume of Material on a Mold	Shackleton, Steven C; McMackin, Ian Matthew, Iad, Pankaj B.; Truskett, Van Nguyen
	7,357,876		15-Apr-2008	Eliminating Printability of Sub-Resolution Defects in Imprint Lithography	Sreenivasan, Sidigata V.
	7,927,541		19-Apr-2011	Full-Wafer or Large Area Imprinting with Multiple Separated Sub-Fields for High Throughput Lithography	Sreenivasan, Sidigata V.
	7,186,656		6-Mar-2007	Method of Forming a Recessed Structure Employing a Reverse Tone Process	Sreenivasan, Sidigata V.
	7,323,417		29-Jan-2008	Method of Forming a Recessed Structure Employing a Reverse Tone Process	Sreenivasan, Sidigata V.
	7,396,475		8-Jul-2008	Method of Forming Stepped Structures Employing Imprint Lithography	Sreenivasan, Sidigata V.
	7,105,452		12-Sep-2006	Method Of Planarizing a Semiconductor Substrate with an Etching Chemistry	Sreenivasan, Sidigata V.
	7,547,504		16-Jun-2009	Pattern Reversal Employing Thick Residual Layers	Sreenivasan, Sidigata V.
	7,179,396		20-Feb-2007	Positive Tone Bi-Layer Imprint Lithography Method	Sreenivasan, Sidigata V.
	7,261,831		28-Aug-2007	Positive Tone Bi-Layer Imprint Lithography Method	Sreenivasan, Sidigata V.
	7,670,953		2-Mar-2010	Positive Tone Bi-Layer Imprint Lithography Method	Sreenivasan, Sidigata V.
	7,858,528		28-Dec-2010	Positive Tone Bi-Layer Imprint Lithography Method	Sreenivasan, Sidigata V.
	7,947,608		24-May-2011	Positive Tone Bi-Layer Imprint Lithography Method	Sreenivasan, Sidigata V.
	7,802,978		28-Sep-2010	Imprinting of Partial Fields at the Edge of the Wafer	Sreenivasan, Sidigata V.; Choi, Byung-Jin

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	7,077,992		18-Jul-2006	Step and Repeat Imprint Lithography Process	Sreenivasan, Sidigata V.; Choi, Byung-Jin; Schumaker, Norman E.; Voisin, Ronald D.; Watts, Michael P.C.; Meissl, Mario Johannes
	8,318,066		27-Nov-2012	Step and Repeat Imprint Lithography Process	Sreenivasan, Sidigata V.; Choi, Byung-Jin; Schumaker, Norman E.; Voisin, Ronald D.; Watts, Michael P.C.; Meissl, Mario Johannes
	7,727,453		1-Jun-2010	Step and Repeat Imprint Lithography Process	Sreenivasan, Sidigata V.; Choi, Byung-Jin; Schumaker, Norman E.; Voisin, Ronald D.; Watts, Michael P.C.; Meissl, Mario Johannes
	7,943,081		17-May-2011	Step and Repeat Imprint Lithography Process	Sreenivasan, Sidigata V.; Choi, Byung-Jin; Schumaker, Norman E.; Voisin, Ronald D.; Watts, Michael P.C.; Meissl, Mario Johannes
	7,179,079		20-Feb-2007	Conforming Template for Patterning Liquids Disposed on Substrates	Sreenivasan, Sidigata V.; Choi, Byung-Jin; Voisin, Ronald D.
	7,699,598		20-Apr-2010	Conforming Template for Patterning Liquids Disposed on Substrates	Sreenivasan, Sidigata V.; Choi, Byung-Jin; Voisin, Ronald D.
	7,491,637		17-Feb-2009	Formation of Conductive Templates Employing Indium Tin Oxide	Sreenivasan, Sidigata V.; McMackin, Ian Matthew; Choi, Byung-Jin; Voisin, Ronald D.
	7,780,893		24-Aug-2010	Method of concurrently patterning a substrate having a plurality of fields and a plurality of alignment marks	Sreenivasan, Sidigata V.; McMackin, Ian Matthew; Melliar-Smith, Christopher M.; Choi, Byung-Jin
	7,795,132		14-Sep-2010	Self-Aligned Cross-Point Memory Fabrication Imprint Lithography Template Having Opaque Alignment Marks	Sreenivasan, Sidigata V.; Melliar-Smith, Christopher M.; LaBrake, Dwayne L.
	7,136,150		14-Nov-2006	Alignment Marks	Sreenivasan, Sidigata V.; Schumaker, Phillip D.
	7,815,824		19-Oct-2010	Real Time Imprint Process Diagnostics for Defects	Sreenivasan, Sidigata V.; Singhal, Shrawan; Choi, Byung-Jin

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	7,241,395		10-Jul-2007	Reverse Tone Patterning on Surfaces Having Surface Planarity Perturbations	Sreenivasan, Sidigata V.; Stacey, Nicholas A.
					Sreenivasan, Sidigata V.; Watts, Michael P.C.; Choi, Byung-jin; Meissl, Mario Johannes; Schumaker, Norman E.; Voisin, Ronald D.
	6,900,881		31-May-2005	Step and Repeat Imprint Lithography Systems	Sreenivasan, Sidigata V.; Watts, Michael P.C.; Choi, Byung-jin; Voisin, Ronald D.
	6,916,584		12-Jul-2005	Alignment Methods for Imprint Lithography	Sreenivasan, Sidigata V.; Watts, Michael P.C.; Choi, Byung-jin; Voisin, Ronald D.
					Sreenivasan, Sidigata V.; Watts, Michael P.C.; Choi, Byung-jin; Voisin, Ronald D.; Schumaker, Norman E.
	7,070,405		4-Jul-2006	Alignment Methods for Imprint Lithography	
				Method of Compensating for a Volumetric Shrinkage of a Material Disposed upon a Substrate to Form a Substantially Planar Structure Therefrom	Sreenivasan, Sidigata V.; Xu, Frank Y.
	7,244,386		17-Jul-2007	Patterning Substrates Employing Multi-Film Layers Defining Etch Differential Interfaces	Stacey, Nicholas A.; Sreenivasan, Sidigata V.; Miller, Michael N.
	7,205,244		17-Apr-2007	Method to Reduce Adhesion Between a Polymerizable Layer and a Substrate Employing a Fluorine-Containing Layer	Truskett, Van Nguyen; Mackay, Christopher J.; Choi, Byung-jin
	7,452,574		18-Nov-2008	Method of Forming an In-situ Recessed Structure	Vidusek, David; Sreenivasan, Sidigata V.; Wang, David C.
	7,252,777		7-Aug-2007	Imprint Alignment Method, System and Template	Voisin, Ronald D.
	7,785,526		31-Aug-2010	Imprint Alignment Method, System and Template	Voisin, Ronald D.
	8,366,434		5-Feb-2013	Methods of Inspecting a Lithography Template	Voisin, Ronald D.
	7,132,225		7-Nov-2006	Methods of Inspecting a Lithography Template	Voisin, Ronald D.
	7,037,639		2-May-2006	Etching Technique to Planarize a Multi-Layer Structure	Wang, David C.; Xu, Frank Y.
	7,259,102		21-Aug-2007	System for Dispensing Liquids	Watts, Michael P.C.; Choi, Byung-jin; Sreenivasan, Sidigata V.
	7,252,715		7-Aug-2007		

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	7,027,156		11-Apr-2006	Scatterometry Alignment for Imprint Lithography	Watts, Michael P.C.; McMackin, Ian Matthew
	7,281,921		16-Oct-2007	Scatterometry Alignment for Imprint Lithography	Watts, Michael P.C.; McMackin, Ian Matthew
	7,071,088		4-Jul-2006	Method for Fabricating Bulbous-Shaped Vias	Watts, Michael P.C.; Sreenivasan, Sidigata V.
	7,279,113		9-Oct-2007	A Method of Forming a Compliant Template for UV Imprinting	Watts, Michael P.C.; Voisin, Ronald D.; Sreenivasan, Sidigata V.
	7,140,861		28-Nov-2006	Compliant Hard Template for UV Imprinting	Watts, Michael P.C.; Voisin, Ronald D.; Sreenivasan, Sidigata V.
	7,759,407		20-Jul-2010	Composition for Adhering Materials Together	Xu, Frank Y.
	8,557,351		15-Oct-2013	Method for Adhering Materials Together	Xu, Frank Y.
				Polymerization Technique to Attenuate Oxygen Inhibition of Solidification of Liquids and Composition Therefor	Xu, Frank Y.; Fletcher, Edward B.; Lad, Pankaj B.; Watts, Michael P.C.
	7,845,931		7-Dec-2010		Xu, Frank Y.; Fletcher, Edward B.; Lad, Pankaj B.; Watts, Michael P.C.
					Xu, Frank Y.; Khusnatdinov, Niyaz; McMackin, Ian Matthew; Stacey, Nicholas A.; Babbs, Daniel A.; Voth, Duane; Watts, Michael P.C.; Truskett, Van Nguyen; Voisin, Ronald D.; Lad, Pankaj B.; Ezekoye, Ofofike A.
	8,211,214		3-Jul-2012	Single Phase Fluid Imprint Lithography Method	Xu, Frank Y.; Lad, Pankaj B.; McMackin, Ian Matthew; Truskett, Van Nguyen; Fletcher, Edward B.
	8,268,220		18-Sep-2012	Imprint Lithography Method	Xu, Frank Y.; Lad, Pankaj B.; McMackin, Ian Matthew; Truskett, Van Nguyen; Fletcher, Edward B.
				Method of Providing Desirable Wetting and Release Characteristics Between a Mold and a Polymerizable Composition	Xu, Frank Y.; Lad, Pankaj B.; McMackin, Ian Matthew; Truskett, Van Nguyen; Fletcher, Edward B.
	7,837,921		23-Nov-2010		Xu, Frank Y.; Mackay, Christopher J.; Lad, Pankaj B.; McMackin, Ian Matthew; Truskett, Van Nguyen; Martin, Wesley; Fletcher, Edward B.; Wang, David C.; Stacey, Nicholas A.; Watts, Michael P.C.
	7,939,131		10-May-2011	Method To Provide A Layer With Uniform Etch Characteristics	

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	8,142,703		27-Mar-2012	An Imprint Lithography Method	Xu, Frank Y.; McMackin, Ian Matthew; Lad, Pankaj B.
	7,307,118		11-Dec-2007	Composition to Reduce Adhesion between a Conformable Region and a Mold	Xu, Frank Y.; Miller, Michael N.
	7,122,079		17-Oct-2006	Composition for an Etching Mask Comprising a Silicon-Containing Material	Xu, Frank Y.; Miller, Michael N.; Watts, Michael P.C.
	7,906,180		15-Mar-2011	Composition for an Etching Mask Comprising a Silicon-Containing Material	Xu, Frank Y.; Miller, Michael N.; Watts, Michael P.C.
	7,282,550		16-Oct-2007	Method To Provide A Layer With Uniform Etch Characteristics	Xu, Frank Y.; Stacey, Nicholas A.
	7,122,482		17-Oct-2006	Methods for Fabricating Patterned Features Utilizing Imprint Lithography	Xu, Frank Y.; Stacey, Nicholas A.; Watts, Michael P.C.; Thompson, Eron D.
				Method for Imprint Lithography Utilizing an Adhesion Primer Layer	Xu, Frank Y.; Sreenivasan, Sidigata V.; Fletcher, Edward B.
11/734,542		12-Apr-2007		Ultra-thin Polymeric Adhesion Layer	Xu, Frank Y.; Fletcher, Edward B.
12/326,709		2-Dec-2008		Imprinting of Partial Fields at the Edge of the Wafer	Sreenivasan, Sidigata V.; Choi, Byung-Jin
13/098,959		2-May-2011		Large Area Roll-to-Roll Imprint Lithography	Sreenivasan, Sidigata V.; Singhal, Shrawan; Choi, Byung-Jin; McMackin, Ian Matthew
	8,187,515		29-May-2012	Large Area Roll-to-Roll Imprint Lithography	Sreenivasan, Sidigata V.; Yang, Shuqiang; Xu, Frank Y.; Labrake, Dwayne L.
	8,529,778		10-Sep-2013	Large Area Patterning of Nano-Sized Shapes	Xu, Frank Y.; Watts, Michael P.C.; Stacey, Nicholas A.
	8,076,386		13-Dec-2011	Materials for Imprint Lithography	Sreenivasan, Sidigata V.; Yang, Shuqiang; Xu, Frank Y.; Singh, Vikramjit
12/854,359		11-Aug-2010		Functional Nanoparticles	Yang, Shuqiang; Miller, Michael N.; Hilali, Mohamed; Wan, Fen; Schmid, Gerard M.; Wang, Liang; Sreenivasan, Sidigata V.; Xu, Frank Y.
13/105,422		11-May-2011		NANOSTRUCTURED SOLAR CELL	
				Nanoimprint Lithography Formation of Functional Nanoparticles Using Dual Release Layers	Singh, Vikramjit; Xu, Frank Y.; Sreenivasan, Sidigata V.
13/289,601		4-Nov-2011			

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13/290,770		7-Nov-2011		PATTERNING OF NON-CONVEX SHAPED NANOSTRUCTURES	Sreenivasan, Sidigata V.; Singh, Vikramjit; Xu, Frank Y.; Choi, Byung-Jin
13/398,442		16-Feb-2012		High Aspect Ratio Patterning of Silicon	Miller, Michael N.; Wan, Fen; Singh, Vikramjit; Donaldson, Darren D.; Schmid, Gerard M.; Sreenivasan, Sidigata V.; Xu, Frank Y.
14/021,463		9-Sep-2013		Large Area Patterning of Nano-Sized Shapes	Sreenivasan, Sidigata V.; Yang, Shuang; Xu, Frank Y.

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